

ASMEX.186DV1



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Raaijmakers et al.
Appl. No. : 09/764,711
Filed : January 18, 2001
For : METHOD OF DEPOSITING
SILICON WITH HIGH STEP
COVERAGE
Examiner : A. Roman

Group Art Unit 2812

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to:
Commissioner for Patents, P.O. Box 1450,
Alexandria, VA 22313-1450, on

May 8, 2003

(Date)

Adeel S. Akhtar
Adeel S. Akhtar, Reg. No. 41,394

AMENDMENT AND RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed on February 24, 2003, please amend the above-captioned application as follows:

INTRODUCTORY COMMENTS

In the Office Action mailed on February 24, 2003, the Examiner rejected all originally pending claims, Claims 33-37. In the present Amendment and Response to Office Action, Applicants have amended Claim 33. Applicants have also added Claim 38. Consequently, after the present Amendment, Claims 33-38 are pending in the instant Application.

Applicants respectfully request full consideration of the amendments and of the remarks contained herein.